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Patent Application No. 10/712,196
Docket No. JSF02-0004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5 Applicant(s): Chang-Feng Wan) Art Unit: 2811
 Serial No.: 10/712,196⁶) Examiner: Shouxiang Hu
 Filed: 05/09/2002)
10 For: **SYSTEM AND METHOD OF FABRICATING MICRO CAVITIES**

Director of the US Patent and Trademark Office
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on 9/15/2005

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AMENDMENT

In response to the Office Action dated 05 May 2005, in response to communication filed on 25 February 2005. Please 5 amend the above-identified patent application as follows:

In the figures

Please find attached figures for insertion.

10

In the claims

Please withdraw claims 22-27 from consideration as claims pursuant to Examiner's restriction requirement.

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Please amend the claims as follows:

1. (Currently amended)

A method of manufacturing a plurality of micro 20 enclosures on a substrate wafer, comprising steps of:

(1) bonding a cap wafer to said substrate wafer with an adhesive layer;

~~(2) thinning said cap wafer to desired thickness;~~